

LISTING OF THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claims 1-12 (Canceled)

Claim 13 (Currently Amended)

A substrate treating apparatus for performing a predetermined treatment of a plurality of substrates as immersed in a heated treating solution, comprising:

a treating tank for having the heated treating solution stored therein;

a substrate transport mechanism that transports the plurality of substrates;

a substrate holding device that holds the substrates received from said substrate transport mechanism and immerses the substrates in the heated treating solution stored in said treating tank; and

a controller that controls the treatment of the substrates by immersing said substrate holding device holding the substrates in the heated treating solution stored in said treating tank;

wherein said substrate holding device includes a plurality of holding rods for holding the plurality of substrates in vertical posture, and a back plate supporting said holding rods in cantilever fashion, said back plate having a heating device; and

said heating device preheats said back plate in a position above said treating tank before said substrate holding device receives the substrates from said substrate transport mechanism and before said substrate holding device is lowered to immerse ~~before immersing~~ the received substrates in the heated treating solution stored in said treating tank.

Claim 14 (Original)

A substrate treating apparatus as defined in claim 13, wherein said heated treating solution is a phosphoric acid solution.

Claim 15 (Original)

A substrate treating apparatus as defined in claim 13, wherein said heated treating solution is sulfuric acid.

Claim 16 (Original)

A substrate treating apparatus as defined in claim 13, wherein said predetermined treatment of said substrates as immersed in said heated treating solution is etching treatment.